



PATENT Attorney Docket No. SEL 139 DIV

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:)	I hereby certify that this correspondence is being
	Shunpei Yamazaki et al.)	deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231
Serial	No.: 09/808,162)	on May 4, 2001 Signature Johns Janus Mons
Filed: March 13, 2001		Ś	Date 5/4/2001
For:	Method For Fabricating A Semiconductor Device))	

Commissioner for Patents Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Dear Sir/Madam:

Pursuant to 37 C.F.R. §1.97, Applicant hereby calls the Examiner's attention to documents listed on the attached form, which documents may be material to the examination of this application. It is believed that a copy of each of the documents was cited by or submitted to the Patent Office in the parent application, Serial No. 08/871,115, filed June 9, 1997, which is being relied upon for an earlier filing date under 35 USC 120. Accordingly, pursuant to 37 C.F.R. §1.98(d), copies of the documents are not being submitted herewith. If copies of such documents are not available to the Examiner or are otherwise required, Applicant will gladly provide them.

No inference should be drawn that the attached list sets forth a comprehensive investigation of the prior art, that any or all are pertinent to the invention, or that any apparatus disclosed is equivalent to the subject invention.

The citation of the above-discussed documents is not to be construed as an assertion that more pertinent art could not possibly be in existence. Citation of any document herein is not to be

construed as an admission that any subject matter disclosed in the document is necessarily within the inventive field of endeavor, that any disclosure is necessarily prior in time to a particular date which may be relevant to the instant patent application, and/or that any disclosure is otherwise necessarily prior art with respect to the instant invention.

Applicant also respectfully reserves the right to later set forth how the instant invention is distinguished over the disclosure of any document or other art, including the disclosure of those documents discussed herein, that may be cited by the Examiner in rejecting a claim in the instant patent application.

This Information Disclosure Statement is being filed within three months from the filing date of the application. Therefore, under 37 C.F.R. 1.97(b), it is believed that no fee is required. However, if it is determined that a fee is required, please charge our Deposit Account No. 50/1039.

Respectfully submitted,

Stephen B. Heller Registration No. 30,181

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	Attorney Docket No. SEL 139 DIV	Serial No. Not Assigned	
LIST OF PUBLICATIONS CITED BY APPLICANT	<u>Applicant</u> Shunpei YAMAZAKI et al		
	<u>Filing Date</u> Herewith	Group	

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
	4,933,298 5,643,826 5,793,073 5,854,123 5,854,509 5,882,987 5,899,711 5,923,962	06/1990 07/01/97 08/11/98 12/1998 12/1998 03/1999 05/04/99 07/13/99	Hasegawa Ohtani et al Kaminishi et al Sato et al Kumikiyo Srikrishnan Smith Ohtani et al	437 437 257 438 257 435 438 438	62 88 254 507 506 458 162 150	10/25/94 03/01/96 10/11/96 04/28/95
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FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE

OTHER PUBLICATIONS

(Including Author, Title, Date, Pertinent Pages)

- Auberton-Herve, A.J. et al, "Industrial Research Society (Kogyo Chosa Kai)," Electronic Material, pp. 83-87, August, 1977.
- Izumi, K. et al, "C.M.O.S. Devices Fabricated on Buried SiQ, Layer Formed by Oxygen Implantation into Silicon," Electronics Letters, vol. 14, no. 18, pp. 593-597, August 31, 1978.
- Sakaguchi, K. et al, "Current Progress in Epritaxial Layer Transfer (ELURAN)," IEICE Trans. Electron, vol. E80 C, no. 3, pp. 378-387, March, 1997.

EXAMINER:

DATE CONSIDERED:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MFEF form. Draw line through citation if not in conformance and not considered. Include a copy of this form with the next communication to applicant.